

Specification

1. Amendments to the specification filed on 1/11/2011 in response to the Non-Final Rejection mailed on 7/13/2010 are entered.

Allowable Subject Matter

2. Claims 1-27 are allowed.
3. The following is an examiner's statement of reasons for allowance:
Applicants' arguments in the telephone interview on 1/6/2011 and the reply filed on 1/11/2011 are persuasive because the closest prior art of record fails to disclose or render obvious a process for wet-chemical treatment on one side of a silicon wafer on a conveyer means wherein a meniscus is positioned at edges of the wafer.

With respect to claim 1, the closest prior art of record fails to disclose or render obvious a process for wet-chemical treatment of silicon wafer wherein: *"the top side of wafer which is not to be treated is remains above the liquid and the meniscus is positioned at edges of the wafer"* as defined in the applicants' independent and amended claims 1.

With respect to claim 10, the closest prior art of record fails to disclose or render obvious a process for wet-chemical treatment of one side of a silicon wafer wherein: *"the level of the liquid being contacted by the underside is maintained above the level of the bath surface not being contacted by the underside as a result a meniscus forms between the underside and a surface of*

the liquid in the liquid bath" as defined in applicants' independent and amended claim 10.

With respect to claim 27, the closest prior art of record fails to disclose or render obvious a process for wet-chemical treatment of one side of a silicon wafer wherein: "*the conveyor means are positioned within the liquid bath, further an electrically conductive top side which is not to be treated is always positioned above the liquid, and a meniscus is positioned at edges of the wafer*" as defined in applicants' independent claim 27.

EXAMINER'S AMENDMENT

4. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Figure 1. Silicon wafer on a conveyor roll.

Authorization for this examiner's amendment was given in a telephone interview with Attorney Raymond Wagenknecht on 3/7/2011.

5. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to MAKI A. ANGADI whose telephone number is (571)272-8213. The examiner can normally be reached on 8 AM to 4.30 PM.

7. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine G. Norton can be reached on 571-272-1465. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/Nadine G Norton/
Supervisory Patent Examiner, Art Unit 1713

/Maki A Angadi/
Examiner, Art Unit 1713